Our Docket No: 42P10058D

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Applica	ation of:	)		
Han-Ming Wu et al.		)	Examiner:	Not yet assigned
Serial No:	Not yet assigned	)	Art Unit:	Not yet assigned
Filed:	Concurrently Herewith	)		
For:	Purging Gas from a Photolithography Enclosure Between a Mask Protective Device and a Pattern Mask	) ) ) _)		
A Rule 1.53(b) Divisional Application of Serial No.: 09/752,938 Filed: Dec. 29, 2000		) ) _)	Examiner: Art Unit:	Hung Nguyen 2851
	PRELIMINARY	AME	NDMENTS	
Commission P.O. Box 14	ivisional Patent Applications er for Patents 50 VA 22313-1450			
Prior	to examination of the presen	t Rule	1.53(b) divisi	onal application, please
enter the foll	owing amendments and consident	er the f	ollowing rema	rks.
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